

Thermally-stable threshold selector based on CuAg alloy for energy-efficient memory and neuromorphic computing applications

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1 **Thermally-stable threshold selector based on CuAg alloy for energy-efficient memory and**
2 **neuromorphic computing applications**

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19

20 **Abstract**

21 **As a promising candidate for high-density data storage and neuromorphic computing,**
22 **cross-point memory arrays provide a platform to overcome the von-Neumann bottleneck**
23 **and accelerate neural network computation. In order to suppress the sneak-path current**
24 **problem that limits their scalability and read accuracy, a two-terminal selector can be**
25 **integrated at each cross-point to form the one-selector-one-memristor (1S1R) stack. In**
26 **this work, we demonstrate a CuAg alloy-based, thermally-stable and electroforming-free**

27 **selector device with tunable threshold voltage and over 7 orders of magnitude ON/OFF**
28 **ratio. A vertically-stacked 64×64 1S1R cross-point array is further implemented by**
29 **integrating the selector with SiO₂-based memristors. The 1S1R devices exhibit extremely**
30 **low leakage currents and proper switching characteristics, which are suitable for both**
31 **storage class memory and synaptic weight storage. Finally, a selector-based leaky-**
32 **integrate-and-fire neuron is designed and experimentally implemented, which expands**
33 **the application prospect of CuAg alloy selectors from synapses to neurons.**

34

35 **Main**

36 In the era of artificial intelligence (AI) and carbon neutrality, the demand for energy-efficient
37 computing systems capable of solving data-intensive computing tasks is surging rapidly. For
38 example, state-of-the-art machine-learning models such as Generative Pre-trained Transformer-
39 3¹ or switch transformers² can easily incorporate multiple billions of computing parameters.
40 Conventional computing hardware based on von-Neumann architecture experiences major
41 difficulty processing such data-centric workloads, primarily due to the bottleneck of data
42 transfer between the processor and the memory blocks in these systems (also called the
43 “memory wall” problem)³.

44 In order to break the memory wall and achieve energy-saving green AI, the design philosophy
45 of compute-in-memory (CIM) has attracted tremendous interests⁴⁻⁷. Such non-von-Neumann
46 computing systems are often realized with emerging memory technologies such as
47 memristors^{5,8}, phase change memories⁹⁻¹¹, ferroelectric memories¹² or magnetic memories¹³. In
48 particular, CIM chip based on memristors (or resistive random-access memory, RRAM) is one
49 of the most widely-studied candidates due to its advantages of low-power operation, low-cost
50 manufacturing and compatibility with complementary metal oxide semiconductor (CMOS)
51 technology¹⁴⁻¹⁶. In order to achieve RRAM-based CIM with high storage capacity, cross-point
52 array is a favorable scenario in terms of unit cell area ($\sim 4F^2$, where F is the minimum feature

53 size)^{6,17}. However, the RRAM cross-point arrays suffer from the sneak-path current problem,
54 which significantly limits the feasible array size¹⁸⁻²⁰.

55 The one-selector-one-memristor (1S1R) architecture, as a general scheme for high-density
56 cross-point memory arrays, is able to suppress the sneak-path currents while improving the
57 storage density^{6,21-25}. An ideal selector for cross-point arrays features small leakage current in
58 the OFF state, sufficiently low resistance in the ON state, steep switching slope (SS) as well as
59 tunable threshold voltage (V_{th}) that can match the memristors for joint operations²⁶. As of today,
60 selector devices based on insulator-metal transition (IMT)^{27,28}, ovonic threshold switching
61 (OTS)^{29,30}, Cu-containing mixed-ionic-electronic conduction (MIEC)^{31,32} and metal-filament-
62 based threshold switching^{33,34} have been considered for 1S1R integration. The IMT selectors
63 with NbO_x or VO₂ switching layer do not require electroforming, but have relatively high
64 leakage currents and is susceptible to ambient temperature change, making it difficult to achieve
65 large array operations^{27,28}. OTS selectors also exhibit limited selectivity ($\sim 10^3$), and its high-
66 temperature stability for backend-of-line (BEOL) integration is yet to be demonstrated^{29,30}.
67 MIEC-based selectors possess high ON/OFF ratio and promising integration potential, but
68 exhibit relatively gradual SS^{31,32}. Finally, metal-filament selectors have sufficiently small
69 leakage currents and abrupt switching, but often lack stability under high-temperature
70 annealing³⁵. In particular, Ag-based metal-filament selectors suffer from the self-agglomeration
71 of Ag under BEOL thermal budget^{36,37}, whereas Cu-based selectors typically require higher
72 electroforming voltages before normal operations³⁴. Therefore, new selector technology with
73 high temperature stability, electroforming-free feature, steep SS and suitable ON and OFF
74 currents is highly desired.

75 Furthermore, selectors and 1S1R arrays have potential applications in neuromorphic
76 computing which adopts certain features of the biological neural systems to accelerate
77 processing and mimic human brain. For example, spiking neural networks (SNN)^{16,38} and
78 Hopfield neural networks (HNN)^{5,39} based on memristor crossbars have been widely explored.

79 SNN uses pulses to encode input information which mimics the working pattern of the brain,
80 potentially offering better energy efficiency for AI computing tasks⁹. HNN based on memristors
81 has been explored for applications such as associative memory³⁹, pattern recognition⁴⁰ and
82 solution of non-deterministic polynomial-time-hard problems⁵. However, for practical
83 SNN/HNN applications, large cross-point arrays (e.g. 64×64 or larger^{5,41}) are desired which
84 share the same sneak-path current problem as cross-point memories, i.e. the initial weight data
85 cannot be properly programmed into large arrays without selectors (See Methods and
86 Supplementary Fig. 1 for array simulations). In this regard, thermally-stable selectors with high
87 selectivity ($>10^6$) are necessary, but are rarely demonstrated in the form of large 1S1R arrays
88 due to integration challenges⁴². Also, selector devices are solely utilized to implement the
89 synaptic functions so far, while the volatile and hysteresis nature of selector switching is
90 inherently suitable for implementing oscillatory neurons^{9,43}.

91 In this work, we demonstrate for the first time that CuAg alloy as an electrode material of
92 selectors exhibits superior thermal stability (400 °C/1 hour) compared to either Ag or Cu
93 electrodes, making it compatible with CMOS BEOL processing. The high ON current, large
94 ON/OFF ratio ($>10^7$), electroforming-free feature and adjustable V_{th} of the proposed
95 CuAg/SiO₂/CuAg selector confirm its feasibility for large 1S1R cross-point arrays.
96 Subsequently, a functional 64×64 1S1R cross-point array is experimentally demonstrated by
97 vertically integrating the CuAg/SiO₂/CuAg selector with Pt/SiO₂/TiN RRAM, exhibiting
98 significant suppression of sneak-path currents and enhanced computational accuracy as
99 synapses. Furthermore, we demonstrate that the proposed selector can be turned into a compact
100 leaky integrate-and-fire (LIF) neuron by simply adding one resistor and one capacitor in parallel,
101 which is a rigorous physical analog of the LIF neuron model. These results suggest that the
102 CuAg alloy-based selector is a promising and reliable new candidate for cross-point memory
103 and neuromorphic computing applications.

104

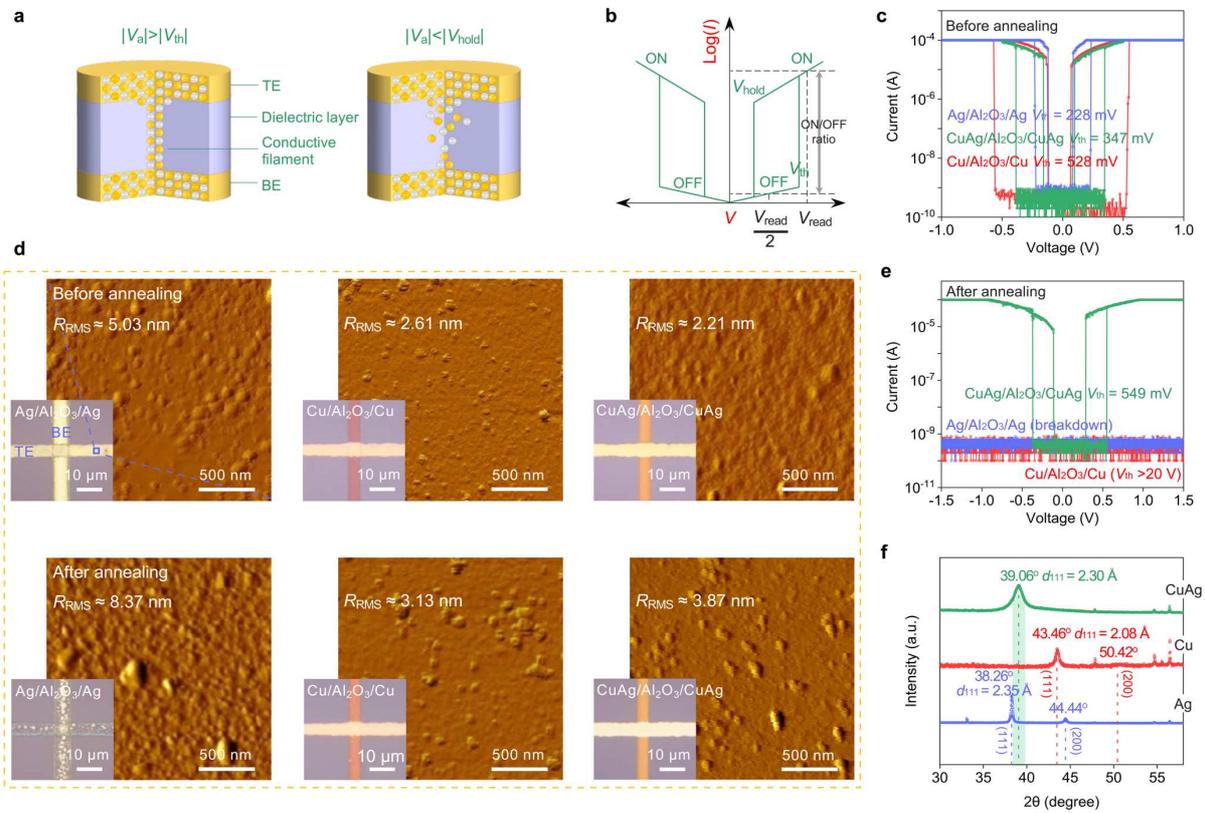
105 **Results and discussion**

106 **CuAg alloy-based selector with high temperature stability**

107 Figure 1a,b demonstrates the device concept and working principles of the Cu/Ag metal-
108 filament-based selector device. These two metals can be injected into the intermediate dielectric
109 layer and form a conductive path when applying sufficient electric field, and the switching can
110 be volatile due to agglomeration and surface-tension effects^{44,45}. In this study, the CuAg alloy
111 is adopted as the electrode material³⁴, which is previously known for its tunable optical
112 properties⁴⁶, outstanding mechanical strength⁴⁷, durability and oxidation resistance^{48,49}. Here,
113 the thermal stability of symmetrical Ag/Al₂O₃/Ag, Cu/Al₂O₃/Cu and CuAg/Al₂O₃/CuAg cross-
114 point selector arrays are firstly investigated, where the Cu, Ag and CuAg are prepared as bottom
115 electrodes (BE) and top electrodes (TE) by magnetron sputtering. The Al₂O₃ interlayer is
116 deposited by thermal atomic layer deposition (ALD) at 200 °C (See Methods). Ag/Al₂O₃/Ag,
117 CuAg/Al₂O₃/CuAg, and Cu/Al₂O₃/Cu selectors all exhibit steep threshold switching
118 characteristics after electroforming process and show increasing V_{th} (Fig. 1c) that varies with
119 the electrode type.

120 In order to simulate the compatibility of the devices with the BEOL processes, the devices
121 are subjected to a high-temperature annealing process (400 °C, Ar atmosphere, 3 mTorr, hold
122 time 1 hour) and their root-mean-square roughness (R_{RMS}) is determined by atomic force
123 microscopy (AFM). As shown in Fig. 1d, Ag/Al₂O₃/Ag devices exhibit significant self-
124 agglomeration after annealing. The R_{RMS} of the annealed device increases tremendously
125 compared to the initial R_{RMS} (from 5.03 to 8.37 nm). In contrast, the stacks of Cu/Al₂O₃/Cu and
126 CuAg/Al₂O₃/CuAg maintain similar morphology before and after annealing, in which the R_{RMS}
127 changes from 2.61 and 2.21 nm to 3.13 and 3.87 nm, respectively. In addition, the annealing
128 process significantly degrades the threshold switching functionality of both Ag/Al₂O₃/Ag and
129 Cu/Al₂O₃/Cu devices. The Ag/Al₂O₃/Ag devices become open, while the V_{th} of Cu/Al₂O₃/Cu
130 devices significantly increases to above 20 V probably due to copper oxidation even though the

131 structure seems intact (Fig. 1e and Supplementary Fig. 2). Intriguingly, the CuAg/Al₂O₃/CuAg
 132 device still maintains the threshold switching characteristics after annealing ($V_{th}=549$ mV). The
 133 crystalline structures of the Ag, Cu and CuAg thin films (~200 nm), which are deposited on
 134 Si/SiO₂ substrates, are subsequently characterized by X-ray diffraction (XRD, Fig. 1f).
 135 Combining the results of XRD, scanning transmission electron microscope (STEM,
 136 Supplementary Fig. 3a) and corresponding energy dispersive X-ray spectroscopy (EDS)
 137 (Supplementary Fig. 3b,c) indicates that the CuAg film is an alloy with an interplanar spacing
 138 of 2.30 Å and an Ag/Cu atomic ratio of ~5:3.



139
 140 **Fig. 1 Exploration of the CuAg alloy-based selector.** **a**, Schematic illustrations of a metal-
 141 filament-based selector under different applied voltage (V_a). **b**, Representative current-voltage
 142 ($I-V$) characteristics of a Cu/Ag metal-filament-based selector, the ON/OFF ratio corresponds
 143 to the current variation at the read voltage (V_{read}) and half-read voltage ($V_{read}/2$). **c**, $I-V$
 144 characteristics of Ag/Al₂O₃/Ag, Cu/Al₂O₃/Cu and CuAg/Al₂O₃/CuAg selectors before
 145 annealing. **d**, Surface morphologies of Ag/Al₂O₃/Ag, Cu/Al₂O₃/Cu and CuAg/Al₂O₃/CuAg

146 devices before and after annealing in Ar atmosphere at 400 °C for 1 hour. **e**, I - V characteristics
147 of annealed Ag/Al₂O₃/Ag, Cu/Al₂O₃/Cu and CuAg/Al₂O₃/CuAg selectors. **f**, XRD patterns of
148 the Ag, Cu and CuAg films on SiO₂/Si substrates.

149

150 As a standard CMOS BEOL oxide, SiO₂-based selectors are further constructed (See
151 Methods). Symmetric CuAg/SiO₂/CuAg cross-point architecture is prepared as illustrated in
152 Fig. 2a and Supplementary Fig. 4a,d. The R_{RMS} of SiO₂ interlayer (90 nm thickness) is ~1.95
153 nm, and the valence state of Si is determined to be dominant Si⁴⁺ (103.3 eV) (Supplementary
154 Fig. 4b,c). The tunable V_{th} is achieved by varying the thickness of SiO₂, where the thicknesses
155 are determined by AFM on patterned SiO₂ films (Supplementary Figs. 5 and 6). In order to
156 better evaluate the ON/OFF ratio, a Keithley 6430 source meter with a higher precision is used
157 to measure the switching characteristics of the CuAg/SiO₂(90 nm)/CuAg selector. The
158 CuAg/SiO₂(90 nm)/CuAg device demonstrates stable symmetric threshold switching
159 characteristics with a superior SS of <0.3 mV decade⁻¹ and an average V_{th} of 316 mV when the
160 compliance current (I_{CC}) is set to be 100 μ A (Fig. 2a and Supplementary Fig. 6d). The device's
161 leakage current is at least smaller than 10⁻¹¹ A and the ON/OFF ratio is larger than 10⁷ (Fig. 2a),
162 which enables large cross-point arrays that are very difficult to achieve with other categories of
163 selector technologies. Moreover, it should be pointed out that the as-fabricated
164 CuAg/SiO₂/CuAg selectors do not require an electroforming process with voltage higher than
165 V_{th} . This phenomenon can be explained by the lower migration barrier of Ag/Ag⁺ in SiO₂
166 compared to Al₂O₃, which is calculated by ab initio simulations with the edge elastic band
167 method⁵⁰ (Supplementary Fig. 7). In addition, the EDS mappings (Supplementary Fig. 4d) show
168 the diffused Cu and Ag particles, corroborating that the threshold switching of CuAg alloy-
169 based selectors originates from metallic conductive filaments^{15,34}.

170 As mentioned above, high performance selectors need to have sufficiently low leakage
171 current in the OFF state and high drive current in the ON state so as to suppress sneak-path

172 currents and achieve high density arrays on the one hand, and to allow easy memory write and
173 read operations without significant voltage drops on the selector on the other. In these regards,
174 the CuAg/SiO₂(90 nm)/CuAg selector is potentially a promising candidate due to its negligible
175 leakage current (<10 pA), high ON current (>100 μ A), steep SS, electroforming-free feature
176 and superior thermal stability.

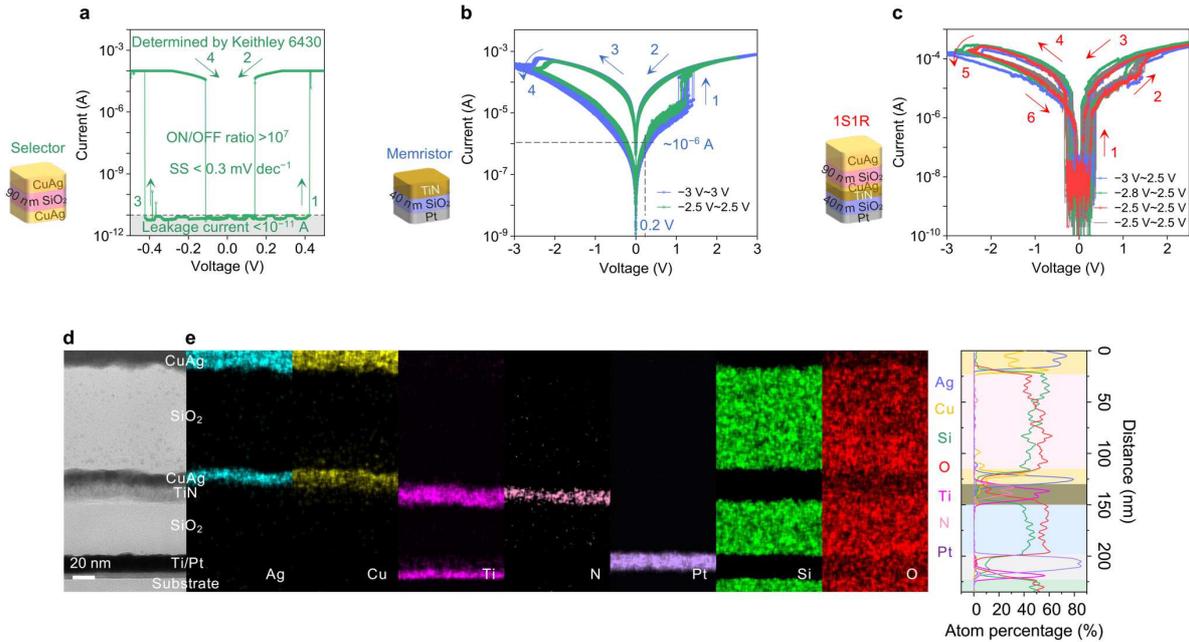
177

178 **64 × 64 1S1R array for synaptic weight storage**

179 To further explore the feasibility of applying CuAg/SiO₂/CuAg selectors in 1S1R arrays, we
180 construct vertically-stacked 64 × 64 1S1R array with CuAg/SiO₂/CuAg selectors and
181 Pt/SiO₂/TiN memristors. Independent Pt/SiO₂(40 nm)/TiN memristors are also prepared and
182 measured for comparison (See Methods). TiN electrode is obtained by reactive magnetron
183 sputtering with N₂/Ar flow of 0.2/20 for optimized electrical conductivity (Supplementary Fig.
184 8). The device characteristics of Pt/SiO₂/TiN memristor are summarized in Fig. 2b, which
185 exhibit typical bipolar resistive switching behaviors with moderate SET and RESET
186 voltages^{51–53}.

187 For 1S1R integration, the manufacturing processes are shown in Supplementary Fig. 9. The
188 as-fabricated CuAg/SiO₂/CuAg/TiN/SiO₂/Pt 1S1R device exhibits the desired DC sweep
189 characteristics (Fig. 2c). The CuAg/SiO₂/CuAg selector acts as a threshold switch with low
190 leakage (<10⁻¹¹ A), significantly suppressing the sneak-path currents in the cross-point array.
191 As the sweep voltage (from CuAg TE to Pt BE) increases, the current of 1S1R device first
192 sharply increases at ~0.3 V (V_{th}), completing the threshold switch (arrow 1, Fig. 2c). Then, a
193 second current jump occurs at ~1.5 V, indicating the SET process (arrow 2). When the voltage
194 sweeps back to ~0.1V (hold voltage, V_{hold}), the current drops and the selector device switches
195 to the OFF state (arrow 3). When the voltage sweeps to negative values, the selector turns on
196 again at ~-0.3 V ($-V_{th}$, arrow 4), followed by a reduction in current at above -2 V, indicating
197 the RESET process (arrow 5). Finally, after the negative voltage sweeps back to ~-0.1 V

198 ($-V_{\text{hold}}$), the current drops again and the device returns to the HRS (arrow 6). A full switching
 199 cycle is hence completed. To visualize the stacking of 1S1R devices, the cross-sectional profile
 200 is extracted by focused ion beam milling in the middle of one 1S1R device, where the stacking
 201 order of the electrodes and dielectric layers can be clearly observed using STEM and EDS (Fig.
 202 2d, e).



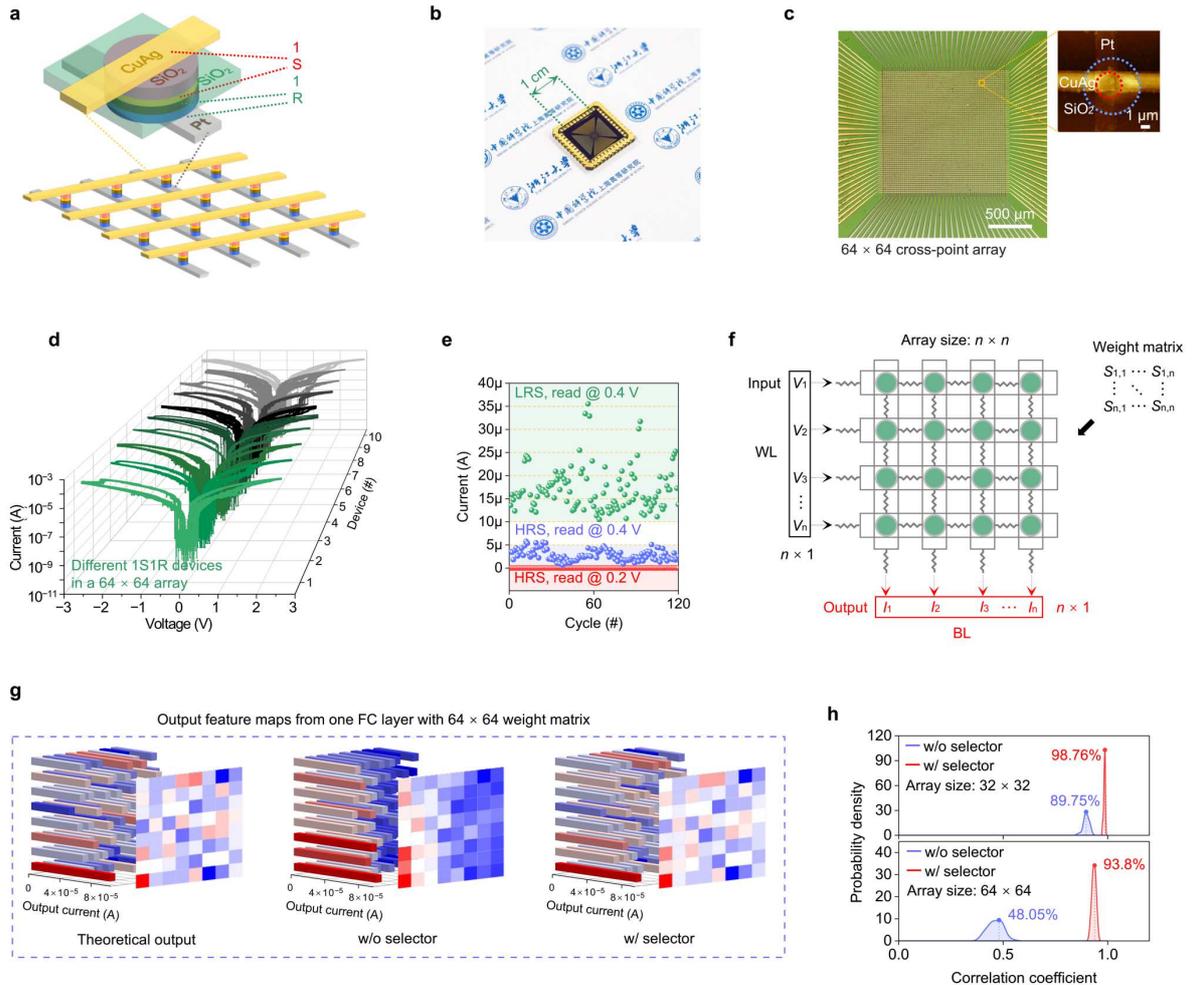
203
 204 **Fig. 2 SiO₂-based selector, memristor and 1S1R device.** **a**, $I-V$ characteristics of the
 205 CuAg/SiO₂(90 nm)/CuAg selector as determined by Keithley 6430. **b**, $I-V$ characteristics of
 206 the Pt/SiO₂/TiN memristor in DC voltage sweep cycles with different stop voltages, the
 207 Pt/SiO₂/TiN memristor exhibits typical SET and RESET processes. **c**, $I-V$ characteristics of the
 208 1S1R device in DC voltage sweep cycles with different stop voltages. **d**, Cross-sectional STEM
 209 image of one 1S1R device. **e**, The EDS mapping and linear sweep results with the elements Ag,
 210 Cu, Ti, N, Pt, Si and O corresponding to (**d**).

211
 212 In addition, the potential of the 1S1R array for implementing next-generation memory and
 213 neuromorphic computing is considered. The structure schematic, chip and array photos are
 214 shown in Fig. 3a–c, where various devices in the as-fabricated 64 × 64 1S1R array exhibit

215 expected electrical properties (Fig. 3d). By setting the access voltage (V_{access}) to 0.4 V and the
216 half-access voltage ($V_{\text{access}}/2$) to 0.2 V, the currents of the 1S1R devices in the low resistance
217 state (LRS), high resistance state (HRS) and OFF state are read separately, as shown in Fig. 3e.
218 With the integration of the selector, the leakage current of the memristor reduces from 10^{-6} to
219 $<10^{-11}$ A. Thus, the ON/OFF ratio of 1S1R devices achieves an improvement of 10^5 times
220 relative to the Pt/SiO₂/TiN memristors alone, reducing the power consumption and improving
221 the feasible array size as cross-point memory. Such 1S1R devices have been cycled over 100
222 times without degradation of the memory window and sensing margin, making it a promising
223 candidate for high-density memory applications.

224 Furthermore, we demonstrate the advantages of applying 1S1R to synaptic weight storage by
225 performing simulations of vector matrix multiplication (VMM) using 32×32 and 64×64 cross-
226 point arrays, with and without selectors (See Methods for array simulations). Figure 3f shows
227 a schematic of the simulation procedure, in which the input vector and binary weight matrices
228 are randomly generated⁵⁴⁻⁵⁶. The weights are encoded in the form of RRAM conductance
229 matrix (S) in which LRS corresponds to '1' and HRS corresponds to '0'. During the simulations,
230 the LRS resistances are generated using the measured distribution and the ON/OFF ratios of
231 RRAM and 1S1R are assumed to be 100 and 10^7 , respectively. The output results in terms of
232 BL currents are simulated with one fully-connected (FC) layer of 64×64 or 32×32 weight
233 matrices, as shown in Fig. 3g and Supplementary Fig. 10. These results indicate that the arrays
234 with selectors are able to generate much more similar output feature maps to the theoretical
235 values than those without selectors. In order to quantify the accuracy of VMM computation, the
236 correlation coefficient of the simulated output vector (IR drop and sneak-path currents
237 considered) versus the theoretical output (by floating-point calculation) is calculated. The
238 probability density of the correlation coefficients obtained from 1000 sets of random inputs are
239 shown in Fig. 3h. It can be concluded that cross-point arrays with selectors achieve much higher
240 VMM accuracy compared to those without selectors (93.8% vs. 48.05% for 64×64 array).

241 Also, as the array size increases, the accuracy degradation increases much faster without
 242 selectors which poses a major challenge for large synaptic arrays. Through eliminating the
 243 sneak-path currents, the as-fabricated 1S1R device can strongly suppress the accuracy
 244 degradation and enable much larger arrays of synaptic data to be accessed simultaneously,
 245 boosting the energy efficiency.



246
 247 **Fig. 3 The 64×64 1S1R array.** **a**, Schematic illustration of the integrated 1S1R devices. **b**,
 248 Photo of the integrated 64×64 1S1R chip. **c**, Optical micrograph of the 64×64 1S1R array.
 249 The inset shows an AFM image of one 1S1R device. **d**, I - V characteristics of different 1S1R
 250 devices in a 64×64 array. **e**, Cycling characteristics of the 1S1R devices. **f**, Schematic diagram
 251 of VMM simulation using cross-point array, where the voltage vector input to the word line
 252 (WL) is a random value and the current after VMM is output from the bit line (BL). **g**, Output
 253 feature map obtained by VMM simulation using one FC layer with 64×64 weight matrix for

254 the theoretical output (left), without selector (middle), and with selector (right), respectively. **h**,
255 Probability density of the correlation coefficients between the theoretical results and the output
256 results obtained by generating 1000 random sets of voltage vectors and weight matrices fed into
257 the RRAM matrix with and without selector.

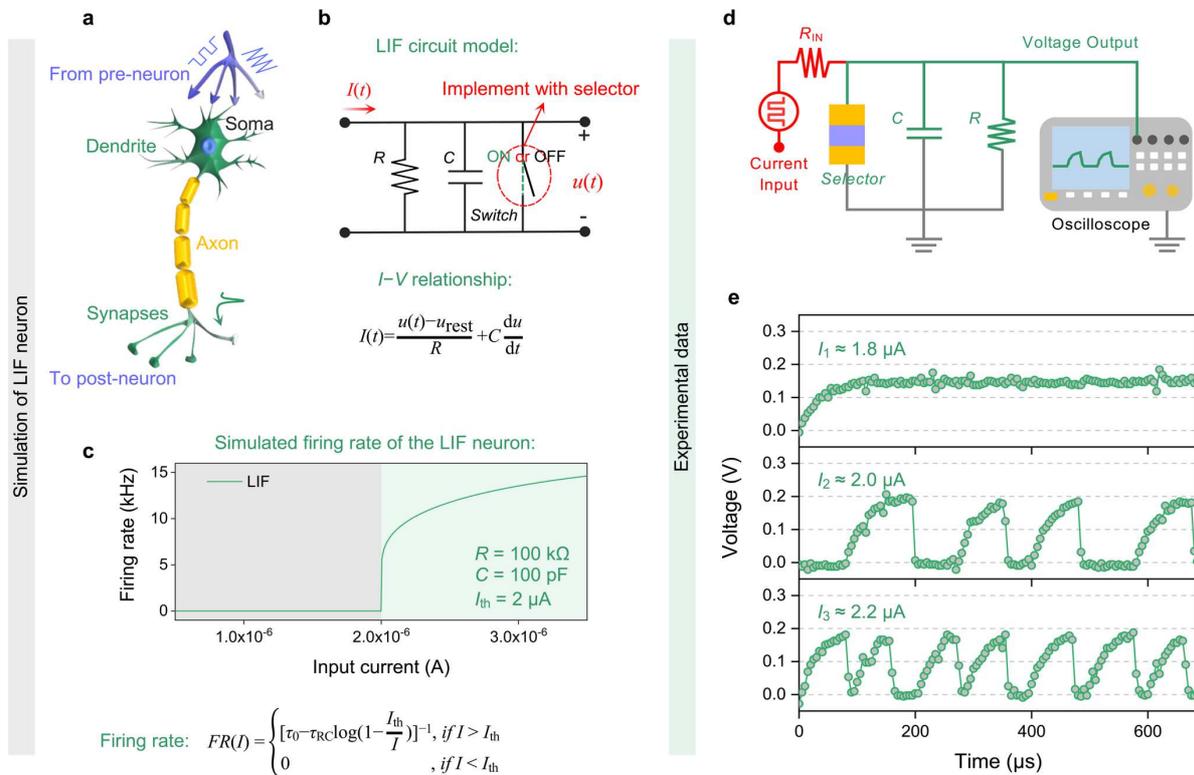
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259 **Selector-based LIF neuron**

260 The LIF neuron is an important classical biological neuron model which has been widely
261 studied and adopted to mimic the human brain⁵⁷ (Fig. 4a). The LIF model features a “leaky”
262 resistor and a capacitor connecting in parallel with a switch, the voltage across which represents
263 the membrane potential of the biological neuron (Fig. 4b). So far, there have been many
264 attempts to emulate LIF model with CMOS analog circuits⁵⁸ or non-volatile memories such as
265 NOR Flash⁵⁹ or FeFET⁶⁰. Figure 4c depicts a key feature of the LIF neuron: there is a minimal
266 input for the neuron to reach the threshold and fire, and once the threshold is reached, the firing
267 frequency increases almost linearly with increasing input. By setting the refractory period (τ_0),
268 RC time constant (τ_{RC}) and threshold current (I_{th}), the variation curve of firing rate with input
269 current in Fig. 4c is simulated. Compared to other selectors with higher leakage (e.g. VO_2 ²⁸,
270 NbO_x ¹⁰, or OTS-based³⁰), the extremely low leakage currents of CuAg alloy-based selectors is
271 the key enabler for implement a LIF neuron. This is because the equivalent leaky resistance of
272 the LIF neuron circuits depends on both the parallel resistor and the OFF state resistance of the
273 switch. With the connection topology of Fig. 4b, the CuAg alloy-based selector’s OFF state
274 resistance and its impact on the parameters of LIF neuron is negligible compared to the parallel
275 resistor, where the value of the parallel resistor can be well controlled in modern integrated
276 circuit design.

277 In order to characterize the behaviors of the proposed LIF neuron, we carry out electrical
278 measurements using the setup shown in Fig. 4d and Supplementary Fig. 11. When a constant
279 current is input to the neuron, it will charge up the capacitor and increase the input node voltage

280 from 0 V, which in turn will induce leakage current through the parallel resistor. If the input
 281 current is smaller than the I_{th} (Fig. 4e), the input node voltage will saturate at a voltage smaller
 282 than the V_{th} of the selector and the neuron will not be fired. On the other hand, if the input
 283 current is above I_{th} , the input node voltage will rise above V_{th} leading to an ON state of the
 284 selector device (i.e. the neuron is fired). The firing of the neuron manifests itself as a high
 285 transient current across the device and the discharge of the parallel capacitor. Based on the
 286 mechanism described above, the I_{th} of the LIF neuron can be derived in terms of the selector
 287 V_{th} : $I_{th}=V_{th}/R$. The firing frequency of the selector-based LIF neuron also increases with the
 288 input current due to the less time needed to charge up the parallel capacitor again. In summary,
 289 the LIF behaviors predicted by the theoretical model have been experimentally observed from
 290 the selector-based LIF neuron. We may conclude that the proposed LIF neuron circuit based on
 291 CuAg alloy selectors is a near-perfect physical analog of the LIF model.



292
 293 **Fig. 4 On the validation of selector-based LIF neuron.** a, Schematic diagram of a biological
 294 neuron. b, Circuit model of a LIF neuron, the relationship between the $I(t)$ and the $u(t)$ is

295 described by the equation in (b), where u_{rest} is the resting membrane potential. c, Simulation of
296 a LIF response function, where the relationship between the firing rate and the input current is
297 described by the equation in (c). d, Circuit for implementing the selector-based LIF neuron. e,
298 Experimental demonstration of the LIF neuron's firing rate with various input currents ($I_1 \approx 1.8$
299 μA , $I_2 \approx 2.0 \mu\text{A}$ and $I_3 \approx 2.2 \mu\text{A}$).

300

301 In summary, we have demonstrated the CuAg alloy-based selector as a promising
302 candidate for high-density cross-point memory and neuromorphic computing applications,
303 which features simple preparation processes, thermally-stable, electroforming-free selector
304 behaviors, tunable V_{th} and over 7 orders of magnitude ON/OFF ratio. Based on this selector
305 device, the proper 1S1R device characteristics in a vertically-stacked 64×64 1S1R cross-point
306 array are achieved, including sufficiently low sneak-path current, desirable I - V curves, stable
307 memory window and switching endurance. Such cross-point arrays can be used to store the
308 synaptic weights of neural networks and achieve more accurate and energy-efficient in-memory
309 computation for AI. A selector-based LIF neuron is also experimentally demonstrated,
310 providing a new perspective for the application of such devices as neurons.

311

312 **Methods**

313 **Device Fabrication.**

314 (1) Al_2O_3 -based selector: The Cu, Ag and CuAg BE are deposited on polished SiO_2 (300 nm)
315 on Si wafers by means of standard photolithography and magnetron sputtering (AJA, ACT
316 Orion 8). Cu and Ag are obtained by magnetron sputtering of 50.8 mm diameter Cu target (99.99%
317 purity) and Ag target (99.99% purity), respectively. During the co-sputtering process, Ag target
318 is sputtered at a radio frequency power of 120 W and Cu target is sputtered at a direct current
319 power of 60 W. Then, Al_2O_3 layer is deposited on the BE by ALD process (200°C, 60 cycles).
320 For a single cycle of ALD, trimethylaluminum (TMA) is first pulsed to 70 Pa for 0.02 s,

321 followed by a 15 s purge. H₂O is then pulsed to 90 Pa for 0.01 s, followed by a 20 s purge. After
322 that, Cu, Ag and CuAg alloy thin films as TE are deposited by photolithography and magnetron
323 sputtering. The Ag/Al₂O₃/Ag, Cu/Al₂O₃/Cu and CuAg/Al₂O₃/CuAg selectors are placed in an
324 argon atmosphere (3 mTorr) at a heating rate of 0.3 °C per second to 400 °C and maintained for
325 1 hour, followed by a slow cooling to room temperature.

326 (2) CuAg/SiO₂/CuAg selectors: Patterned CuAg as BE and TE are deposited at room
327 temperature by means of photolithography and magnetron sputtering (AJA, ACT Orion 8). SiO₂
328 films with different thicknesses are obtained by electron beam evaporation with acceleration
329 voltage of 10 kV at room temperature (99.99% purity of SiO₂ particles, evaporation rate: ~5
330 Å/s).

331 (3) Pt/SiO₂/TiN memristors: Patterned Ti/Pt (5/15 nm) as BE are deposited at room
332 temperature by means of photolithography and electron beam evaporation (99.99% purity of Ti
333 and Pt particles). The preparation process of SiO₂ films is the same as the previous section.
334 Patterned TiN as TE is deposited at room temperature by sputtering (AJA, ACT Orion 8) Ti
335 target (99.99% purity) in N₂/Ar flow ratio of 0.2 sccm /20 sccm (3 mTorr) at room temperature.

336 (4) The 1S1R array: The 1S1R array consists of CuAg/SiO₂/CuAg selectors and Pt/SiO₂/TiN
337 memristors stacked vertically, and the fabrication steps are detailed in Supplementary Fig. 9.

338 **Materials Characterizations.**

339 Optical microscope images are obtained by 3D laser scanning confocal microscope (Keyence
340 VK9710K). AFM images and Raman spectra are obtained by a combined AFM/Raman (532
341 nm) instrument (NT-MDT NTEGRA). The composition and structural analyses are carried out
342 by XRD (Rigaku D/max2200) and X-ray photoelectron spectroscopy (XPS, Thermo Fisher 250
343 XI). STEM images and corresponding EDS are obtained by FEI Titan Themis 200.

344 **Electrical Measurements.**

345 Electrical characterizations are executed with an Agilent B1500A semiconductor device
346 parameter analyzer, a Keithley 6430 source meter, an Agilent MSO7054A oscilloscope, a

347 Keysight 33250A waveform generator, and a self-made variable resistance box (10 k, 100 k, 1
348 M and 10 M Ω).

349 **Array Simulations.**

350 The input parameters of the $n \times n$ cross-point array simulations include voltage vector applied
351 to the WL [$V_1, V_2, V_3, \dots, V_n$], the weight data in the form of conductance matrix corresponding
352 to all cross-points [$S_{1,1}, \dots, S_{n,n}$], and the line resistances between two adjacent junctions along
353 WLs or BLs (R_{WL}, R_{BL}). The output parameters of VMM are defined as the current vector read
354 from the BLs [$I_1, I_2, I_3, \dots, I_n$] when the BL voltages are fixed at zero. The junction conductance
355 is defined by the measured results of 1S1R devices and the line resistance is defined with
356 empirical values. The cross-point array simulations are performed as SPICE-style simulations
357 of the equivalent circuits implemented in MATLAB. The steady-state electrical characteristics
358 of a cross-point array can be completely described by the WL plane voltages [$V_{WL}(i, j)$] and BL
359 plane voltages [$V_{BL}(i, j)$] at each cross-point, where $1 \leq i, j \leq n$. Based on Kirchhoff's law and
360 the input parameters, these $2 \times n \times n$ voltage variables can be written in matrix form and solved
361 for the currents in an iterative manner. The accuracy of the VMM operations using the cross-
362 point array is characterized by the statistical results of the correlation coefficient between the
363 simulated output current vector and the theoretical output vector, obtained using multiple sets
364 of randomly-generated input parameters (See Supplementary Fig. 1 and Supplementary Table
365 1 for further details).

366

367 **Data availability**

368 The data supporting the findings of this study are available from the corresponding authors
369 upon reasonable request.

370

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510

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516

517 **Author contributions**

518 L. Zhao conceived and designed the experiments and performed the simulation. X. Zhou
519 performed the experiments and measurements. L. Zhao and X. Zhou wrote this paper. C. Yan
520 contributed to the simulation. W. Zhen contributed to the experiments and measurements. Y.
521 Lin, L. Li and G. Du assisted the device fabrications under the supervision of D. Li, L. Lu, S.
522 Zhang and Z. Lu. All authors discussed and reviewed the manuscript. D. Li and L. Zhao
523 supervised the project.

524

525 **Competing interests**

526 The authors declare no competing interests.

527

528 **Additional Information**

529 **Supplementary information** is available for this paper at

530 **Correspondence and requests for materials** should be addressed to Liang Zhao, or

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